202450US0 Docket No.

# TES PATENT AND TRADEMARK OFFICE

IN RE APPLICATION OF:

Atsushi SHIOTA, et al.

09/770,289

SERIAL NO:

GAU:

1712

FILED:

January 29, 2001

EXAMINER: M. Feely

FOR:

PROCESS FOR PRODUCING SILICA-BASED FILM, SILICA-BASED FILM, INSULATING FILM, AND

SEMICONDUCTOR DEVICE

# **INFORMATION DISCLOSURE STATEMENT UNDER 37 CFR 1.97**

COMMISSIONER FOR PATENTS ALEXANDRIA, VIRGINIA 22313

Applicant(s) wish to disclose the following information.

### REFERENCES

- The applicant(s) wish to make of record the references listed on the attached form PTO-1449 and cited in the European Search Report dated June 14, 2004. Copies of the listed references are attached, where required, as are either statements of relevancy or any readily available English translations of pertinent portions of any non-English language references. Appearing in the European Search Report, but not on the form PTO-1449, are EP 1 090 967 (equivalent of US Appl. No. 09/669,859) and EP 1 088 868 (equivalent of US Appl. No. 09/670,547). Both US applications were previously cited in the Information Disclosure Statement filed May 31, 2001.
- A check or credit card payment form is attached in the amount required under 37 CFR §1.17(p).

### RELATED CASES

- ☐ Attached is a list of applicant's pending application(s) or issued patent(s) which may be related to the present application. A copy of the patent(s), together with a copy of the claims and drawings of the pending application(s) is attached along with PTO 1449.
- ☐ A check or credit card payment form is attached in the amount required under 37 CFR §1.17(p).

### **CERTIFICATION**

- Each item of information contained in this information disclosure statement was first cited in any communication from a foreign patent office in a counterpart foreign application not more than three months prior to the filing of this statement.
- □ No item of information contained in this information disclosure statement was cited in a communication from a foreign patent office in a counterpart foreign application or, to the knowledge of the undersigned, having made reasonable inquiry, was known to any individual designated in 37 CFR §1.56(c) more than three months prior to the filing of this statement.

## DEPOSIT ACCOUNT

Please charge any additional fees for the papers being filed herewith and for which no check or credit card payment is enclosed herewith, or credit any overpayment to deposit account number 15-0030. A duplicate copy of this sheet is enclosed.

Respectfully submitted,

OBLON, SPIVAK, McCLELLAND, MAIER & NEUSTADT, P.C.

Norman F. Oblon wen voul Umbach

Corwin P. Umbach, Ph.D.

Registration No. 40,211

Customer Number

Tel. (703) 413-3000 Fax. (703) 413-2220

(OSMMN 05/03)

SHEET OF 1 ATTY DOCKET NO. SERIAL NO. U.S. DEPARTMENT OF COMMERCE PATENT INSTRADEMARK OFFICE Form PTO 1449 (Modified) 202450US0 09/770,289 **APPLICANT** LIST OF REFERENCES CITED BY APPLICANT Atsushi SHIOTA, et al. FILING DATE **GROUP** 1712 January 29, 2001 **U.S. PATENT DOCUMENTS FILING DATE** SUB **EXAMINER** DOCUMENT DATE **CLASS** NAME IF APPROPRIATE INITIAL NUMBER **CLASS** AA ΑB AC AD ΑE AF AG AΗ ΑI ΑJ ΑK AL ΑM ΑN **FOREIGN PATENT DOCUMENTS** DOCUMENT TRANSLATION DATE COUNTRY NUMBER NO YES WO 99/36953 99/22/ל **WIPO** ΑO **WIPO** WO 97/00535 1/3/97 AP EP 1 050 601 11/8/00 EP AQ 6/9/99 EP AR EP 0 921 561 AS ΑT ΑU

# AV OTHER REFERENCES (Including Author, Title, Date, Pertinent Pages, etc.) AW MCCLATCHIE, S. et al. "Low Dielectric Constant Oxide Films Deposited Using CVD Techniques", Dumic Conference Proceedings, February 1998, pages 311-318. AX AY AZ Date Considered

\*Examiner: Initial if reference is considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in

conformance and not considered. Include copy of this form with next communication to applicant.